

FORM PTO-1449 U.S. Department of Commerce Patent and Trademark Office LIST OF DOCUMENTS CITED BY APPLICANT (Use several sheets if necessary)				Attorney Docket Number 5576-120DV		Serial No. To Be Assigned	
				Applicants: Hatakeyama et al.			
				Filing Date Concurrently Herewith		Group To Be Assigned	

U. S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
WA		4,491,628	01/01/85	Ito et al.	430	176	
		5,442,087	08/15/95	Eichhorn et al.	560	12	
		5,529,886	06/25/96	Eichhorn et al.	430	270.1	
		5,612,169	03/18/97	Eichhorn et al.	430	270.1	
		5,741,621	04/1998	Kempt et al.	430	253	
		5,968,712	10/19/99	Thackeray et al.	430	326	
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		Document Number	Date	Country	Class	Subclass	Translation Yes No
WA		05158239 A	06/25/93	JAPAN	G03F	7/038	X (Abstract)
		05232706 A	09/10/93	JAPAN	G03F	7/039	X (Abstract)
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 EXAMINER
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A. Ashton

DATE CONSIDERED

7/8/04

Initial if reference considered, whether or not citation is in conformance with MPEP 609: draw line through citation if not in

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		07120929 A	05/12/95	JAPAN	G03F	7/039	X (Abstract)
		07128859 A	05/19/95	JAPAN	G03F	7/039	X (Abstract)
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
		Hinsberg et al.; "Fundamental Studies of Airborne Chemical Contamination of Chemically Amplified Resists," <i>Journal of Photopolymer Science and Technology</i> 6:4 535-546 (1993).					
		Kumada et al.; "Study on Over-Top Coating of Positive Chemical Amplification Resists for KrF Excimer Laser Lithography," <i>Journal of Photopolymer Science and Technology</i> 6:4 571-574 (1993).					
		U.S. Patent Application No. 06/873,914, Filed: June 13, 1986					